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In accordance with the guidelines and waived provisions of 37 C.F.R. 1.121 promulgated in the USPTO announcement of January 31, 2003, please make the following amendments.

IN THE CLAIMS:

Please amend the claims as follows.

(Corrently Amended) An active matrix display device comprising:

a/substrate having an insulating surface;

/a plurality of pixel electrodes arranged in a matrix form over said substrate;

a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor;

a display medium capable of electrically changing luminous strength disposed at each of said pixel electrodes; and

a driver circuit comprising a plurality of thin film transistors for driving said plurality of switching elements.

wherein each of said plurality of thin film transistors comprises a <u>crystallized</u> erystalline semiconductor layer, a gate insulating film adjacent to said <u>crystallized</u> erystalline semiconductor layer and a gate electrode adjacent to said gate insulating film.

- 2. (Previously Amended) The active matrix display device according to claim 1 wherein said gate electrode is located over said semiconductor layer.
- 3. (Previously Amended) The active matrix display device according to claim 1 wherein all of said plurality of thin film transistors are p-channel transistors.
- 4. (Previously Amended) The active matrix display device according to claim 1 wherein all of said plurality of thin film transistors are n-channel transistors.



- 5.\ (Previously Amended) The active matrix display device according to claim 1 wherein said substrate is a glass substrate.
- 6. (Currently Amended) The active matrix display device according to claim 1 wherein said <u>crystallized</u> erystalline semiconductor layer comprises silicon.
 - 7. (Currently Amended) An active matrix display device comprising:
 - a substrate having an insulating surface;
 - a plurality of pixel electrodes arranged in a matrix form over said substrate;
- a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor;
- a display medium capable of electrically changing luminous strength disposed at each of said pixel electrodes; and
- a driver circuit comprising a plurality of thin film transistors for driving said plurality of switching elements, wherein each of said plurality of thin film transistors comprises a <u>crystallized</u> <u>erystalline</u> semiconductor layer, a gate insulating film adjacent to said <u>crystallized</u> <u>erystalline</u> semiconductor layer and a gate electrode adjacent to said gate insulating film,

wherein said <u>crystallized</u> erystalline semiconductor layer has source and drain regions and at least one lightly doped region.

- 8. (Previously Amended) The active matrix display device according to claim 7 wherein said substrate is a glass substrate.
- 9. (Previously Amended) The active matrix display device according to claim 7 wherein said source and drain regions and said at least one lightly doped region are doped with phosphorus.
 - 10. (Canceled)

- 11. (Previously Amended) The active matrix display device according to claim 7 wherein said gate electrode is located over said semiconductor layer.
- 12. (Original) The active matrix display device according to claim 7 wherein said gate electrode is located over said semiconductor layer.
 - 13. (Currently Amended) An active matrix display device comprising: a substrate having an insulating surface;
 - a plurality of pixel electrodes arranged in a matrix form over said substrate;
- a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor;
- a display medium capable of electrically changing luminous strength disposed at each of said pixel electrodes; and
- a CMOS circuit comprising at least one n-channel thin film transistor and one p-channel thin film transistor,

wherein each of said n-channel and p-channel thin film transistors comprises a <u>crystallized</u> erystalline semiconductor layer, a gate insulating film adjacent to said <u>crystallized</u> erystalline semiconductor layer and a gate electrode adjacent to said gate insulating film.

- 14. (Previously Amended) The active matrix display device according to claim 13 wherein said substrate is a glass substrate.
- 15. (Previously Amended) The active matrix display device according to claim 13 wherein said gate electrode is located over said semiconductor layer.
- 16. (Currently Amended) The active matrix display device according to claim 13 wherein said <u>crystallized</u> <u>erystalline</u> semiconductor layer comprises silicon.
 - 17. (Currently Amended) An active matrix display device comprising: a substrate having an insulating surface;

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a plurality of pixel electrodes arranged in a matrix form over said substrate;

- a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor;
- a display medium capable of electrically changing luminous strength disposed at each of said pixel electrodes; and
- a CMOS circuit comprising at least one n-channel thin film transistor and one p-channel thin film transistor, each of said first and second thin film transistors comprising a <u>crystallized</u> <u>crystalline</u> semiconductor layer, a gate insulating film adjacent to said <u>crystallized</u> <u>crystalline</u> semiconductor layer and a gate electrode adjacent to said gate insulating film,

wherein said <u>crystallized</u> erystalline semiconductor layer has source and drain regions and at least one lightly doped region.

- 18. (Previously Amended) active matrix display device according to claim 17 wherein said substrate is a glass substrate.
 - 19. (Currently Amended) An active matrix display device comprising:
 - a substrate having an insulating surface;
 - a plurality of pixel electrodes arranged in a matrix form over said substrate;
- a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor;
- a display medium capable of electrically changing luminous strength disposed at each of said pixel electrodes; and
- a driver circuit comprising a plurality of thin film transistors for driving said plurality of switching elements,

wherein each of the film transistors of said switching elements and said driver circuit comprises a <u>crystallized</u> erystalline semiconductor layer, a gate insulating film adjacent to said <u>crystallized</u> erystalline semiconductor layer and a gate electrode adjacent to said gate insulating film.

- 20. (Previously Amended) The active matrix display device according to claim 19 wherein said gate electrode is located over said semiconductor layer.
- 21 (Previously Amended) The active matrix display device according to claim 19 wherein all of said plurality of thin film transistors are p-channel transistors.
- 22. (Previously Amended) The active matrix display device according to claim 19 wherein all of said plurality of thin film transistors are n-channel transistors.
- 23. (Previously Amended) The active matrix display device according to claim 19 wherein said substrate is a glass substrate.
- 24. (Currently Amended) The active matrix display device according to claim 19 wherein said <u>crystallized</u> <u>erystalline</u> semiconductor layer comprises silicon.
 - 25. (Currently Amended) An active matrix display device comprising:
 - a substrate having an insulating surface;
 - a plurality of pixel electrodes arranged in a matrix form over said substrate;
- a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor;
- a display medium capable of electrically changing luminous strength disposed at each of said pixel electrodes; and
- a driver circuit comprising a plurality of thin film transistors for driving said plurality of switching elements,

wherein each of the thin film transistors of the switching elements and the driver circuit comprises a <u>crystallized</u> erystalline semiconductor layer, a gate insulating film adjacent to said <u>crystallized</u> erystalline semiconductor layer and a gate electrode adjacent to said gate insulating film,

wherein said <u>crystallized</u> erystalline semiconductor layer has source and drain regions and at least one lightly doped region.

- 26 (Previously Amended) The active matrix display device according to claim 25 wherein said substrate is a glass substrate.
- 27. (Previously Amended) The active matrix display device according to claim 25 wherein said source and drain regions and said at least one lightly doped region are doped with phosphorus.
 - 28. (Canceled)
- 29. (Previously Amended) The active matrix display device according to claim 25 wherein said gate electrode is located over said semiconductor layer.
- 30. (Currently Amended) The active matrix display device according to claim 25 wherein said <u>crystallized</u> <u>erystalline</u> semiconductor layer comprises silicon.
 - 31. (Currently Amended) An active matrix display device comprising:
 - a substrate having an insulating surface;
 - a plurality of pixel electrodes arranged in a matrix form over said substrate;
- a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor;
- a display medium capable of electrically changing luminous strength disposed at each of said pixel electrodes; and
- a CMOS circuit comprising at least one n-channel thin film transistor and one p-channel thin film transistor,

wherein each of the film transistors of the switching elements and said n-channel and p-channel thin film transistors comprises a <u>crystallized</u> erystalline semiconductor layer, a gate insulating film adjacent to said <u>crystallized</u> erystalline semiconductor layer and a gate electrode adjacent to said gate insulating film.

32. (Previously Amended) The active matrix display device according to claim 31 wherein said substrate is a glass substrate.

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- 33. (Previously Amended) The active matrix display device according to claim 31 wherein said gate electrode is located over said semiconductor layer.
- 34. (Currently Amended) The active matrix display device according to claim 31 wherein said <u>crystallized</u> erystalline semiconductor layer comprises silicon.
 - 35. (Currently Amended) An active matrix display device comprising:
 - a substrate having an insulating surface;
 - a plurality of pixel electrodes arranged in a matrix form over said substrate;
- a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor;
- a display medium capable of electrically changing luminous strength disposed at each of said pixel electrodes; and
- a CMOS circuit comprising at least one n-channel thin film transistor and one p-channel thin film transistor,

wherein each of the film transistors of the switching elements and said n-channel and p-channel thin film transistors comprises a <u>crystallized erystalline</u> semiconductor layer, a gate insulating film adjacent to said <u>crystallized erystalline</u> semiconductor layer and a gate electrode adjacent to said gate insulating film, and said <u>crystallized erystalline</u> semiconductor layer has source and drain regions and at least one lightly doped region.

- 36. (Previously Amended) The active matrix display device according to claim 35 wherein said substrate is a glass substrate.
- 37. (Currently Amended) The active matrix display device according to claim 35 wherein said <u>crystallized</u> erystalline semiconductor layer comprises silicon.
- 38. (Currently Amended) The active matrix display device according to claim 17 wherein said <u>crystallized</u> <u>erystalline</u> semiconductor layer comprises silicon.